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PATENT

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Fuerhoff et al.

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

Examiner M. Anderson

December 12, 2003

## **AMENDMENT E**

COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria VA 22313-1450

SIR:

In response to the non-final Office action mailed September 12, 2003, please amend the application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.